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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/781,870	02/20/2004	Weng-Chung Liao	BHT-3230-87 5128  EXAMINER	
75	590 11/02/2005			
TROXELL LAW OFFICE PLLC			СНИ, ЈОНИ S Y	
SUITE 1404 5205 LEESBURG PIKE		ART UNIT	PAPER NUMBER	
FALLS CHURCH, VA 22041			1752	
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DATE MAILED: 11/02/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)		
Office Action Summary					
		10/781,870	LIAO ET AL.		
	Office Action Guillinary	Examiner	Art Unit		
	TI- MAN INO DATE AND	John S. Chu	1752		
Period fo	The MAILING DATE of this communication app or Reply	ears on the cover sheet with the c	orrespondence address		
WHIC - Exte after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DAINS ons of time may be available under the provisions of 37 CFR 1.13 SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period we use to reply within the set or extended period for reply will, by statute, reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tim will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE.	N. nely filed the mailing date of this communication. D. (35 U.S.C. 6.133)		
Status					
1)⊠	Responsive to communication(s) filed on 18 Au	ugust 2005.			
	This action is <b>FINAL</b> . 2b) This action is non-final.				
3)	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is				
	closed in accordance with the practice under E	x parte Quayle, 1935 C.D. 11, 45	53 O.G. 213.		
Disposit	ion of Claims				
5)⊠ 6)⊠ 7)□	Claim(s) <u>1-6</u> is/are pending in the application.  4a) Of the above claim(s) is/are withdrav  Claim(s) <u>1-3</u> is/are allowed.  Claim(s) <u>4-6</u> is/are rejected.  Claim(s) is/are objected to.  Claim(s) are subject to restriction and/or				
Applicati	ion Papers				
9) 10)	The specification is objected to by the Examiner The drawing(s) filed on is/are: a) acce Applicant may not request that any objection to the o Replacement drawing sheet(s) including the correcti The oath or declaration is objected to by the Examiner	epted or b) objected to by the Edrawing(s) be held in abeyance. See ion is required if the drawing(s) is obj	e 37 CFR 1.85(a). jected to. See 37 CFR 1.121(d).		
	under 35 U.S.C. § 119				
12)⊠ a)[	Acknowledgment is made of a claim for foreign  All b) Some * c) None of:  1. Certified copies of the priority documents  2. Certified copies of the priority documents  3. Copies of the certified copies of the priority documents  application from the International Bureau  See the attached detailed Office action for a list of	s have been received. s have been received in Application ity documents have been receive (PCT Rule 17.2(a)).	on No ed in this National Stage		
2) 🔲 Notic 3) 🔲 Inform	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) r No(s)/Mail Date	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal Pa 6) Other:			

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## **DETAILED ACTION**

This Office action is in response to the amendment received August 19, 2005.

## Claim Rejections - 35 USC § 112

1. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

2. Claims 4-6 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

The claimed invention is drawn to the method for high aspect ratio pattern transfer of negative photoresist applications, see below:

Claim 4. (Currently Amended) A method for high aspect ratio pattern transfer of negative photoresist application comprising the steps of:

- (1) obtaining a moldboard which is both being pervious to light and has having a protruding-and-recessing figure to form and forming a masking layer by way of sputtering deposition of a masking material on said moldboard:
- (2) after solidifying the masking layer, obtaining a substrate depositing negative photoresist on said substrate;
- (3) covering said moldboard with said substrate that has said protruding-and-recessing figure for further processing Step and Flash from the said moldboard side:
- (4) after finishing said Step and Flash process, removing said moldboard from said substrate; and
- (5) with developer, washing unexposed portions of the thin film covered with said negative photoresist on said substrate to show the exposed portion whereby produces high aspect ratio pattern.

Claim 5. (Currently Amended) The method according to claim 4, wherein said exposed portion of said negative photoresist forms macromolecule polymerization or is cross-linked after flashing and said unexposed portion can be is washed by an alkaline developer to form pattern needed.

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Claim 4 is indefinite as to how the moldboard for can be previous to light if a masking layer is sputter deposited on the moldboard and there is no grinding step to remove the masking layer.

## 3. Claims 1-3 are allowed.

None of the prior art references disclose the claimed method wherein the mask is grinded after sputtering a masking layer on the moldboard. Here the photoresist is then developed with an aqueous developer, while not etched as recited in the prior art imprint processes.

4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. SREENIVASAN et al (2004/0008334) is cited to disclose imprint lithography with an optical lithography step. The reference lacks the claimed method of making the mask wherein a masking layer is coated on the mold and then grinded to form light pervious sections to allow the light to hit the photosensitive resin layer, see the drawing below:

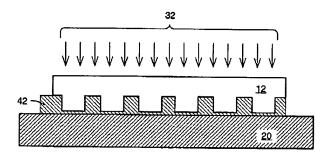


FIG. 23C

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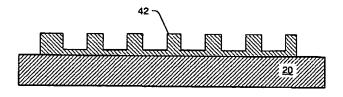


FIG. 23D

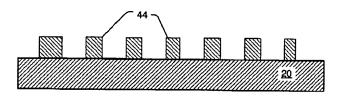


FIG. 23E

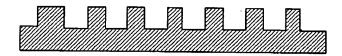


FIG. 23F

BAILEY et al (2004/0141163) likewise discloses an imprint lithography step, however lacks the claimed grinding step to form a mask as claimed, see the image below:

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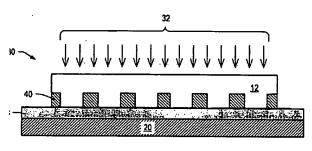
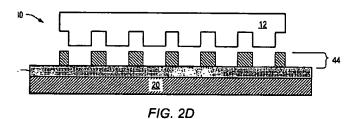
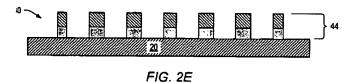


FIG. 2C





5. THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event,

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however, will the statutory period for reply expire later than SIX MONTHS from the mailing

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date of this final action.

6. Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Examiner Chu whose telephone number is (571) 272-1329. The

examiner can normally be reached on Monday - Friday from 9:30 am to 6:00 pm.

The fax phone number for the USPTO is (571) 273-8300.

Any inquiry of a general nature or relating to the status of this application or proceeding

should be directed to the Group receptionist whose telephone number is (571) 272-1700.

Information regarding the status of an application may be obtained from the Patent

Application Information Retrieval (PAIR) system. Status information for published applications

may be obtained from either Private PAIR or Public PAIR. Status information for unpublished

applications is available through Private PMR only. For more information about the PAIR

system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR

system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

John S. Chu

Primary Examiner, Group 1700

J.Chu October 30, 2005